High Sensitivity Piezomagnetic Force Microscopy for Quantitative Probing of Magnetic Materials at the Nanoscale

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Supporting Information

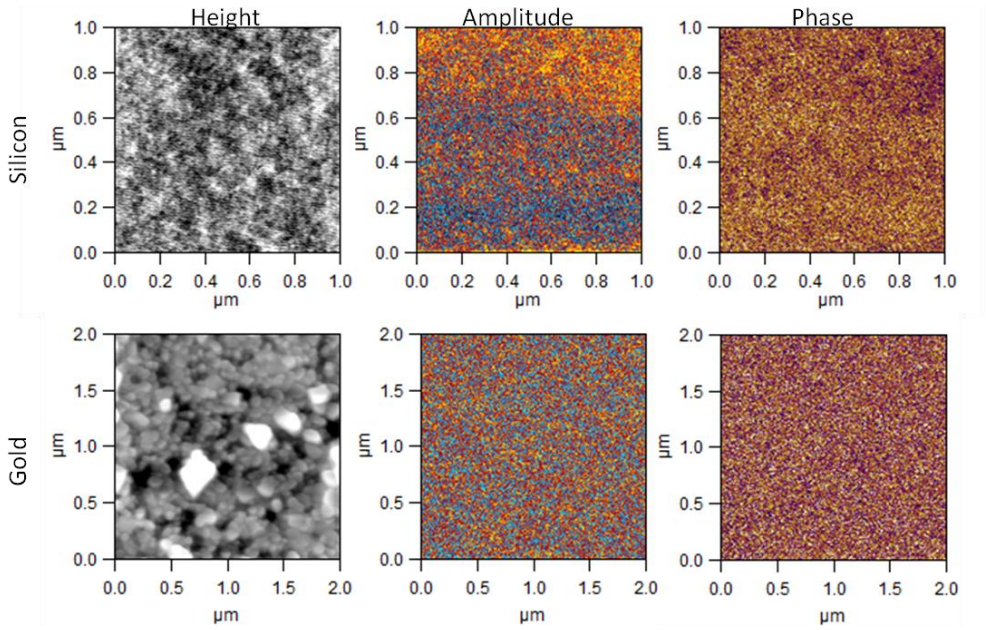

Fig. S1 PmFM probing of silicon and gold-coated silicon, showing featureless mappings.

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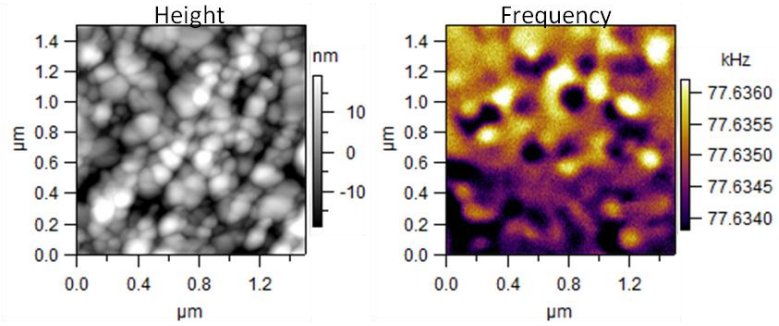

Fig. S2 MFM of CFO film, showing limited contrast and spatial resolution.